RG-200PV SEMI-AUTO
SHEET RESISTANCE/RESISTIVITY MEASUREMENT

RG-200PV

- Multi-point, Contact Type PC controlled via software
- 4-point probe measurement method
- X-Y moving mechanism for solar cell wafer
- User programmable measurement pattern
- Tester self-test function
- Thickness, edge, temperature correction for silicon wafer
- Measure Range:
  - ✓ Resistivity: 1mΩ.cm to 10kΩ.cm
  - ✓ Sheet Resistance: 1mΩ/sq to 1MΩ/sq
- Sample Size: 210mm x 210mm
- Other sample size on request
- For FPD, model RG-100

APPLICABLE MATERIALS

- Semiconductor and Solar-cell materials (Silicon, Polysilicon, SiC etc)
- Functional materials (Carbon nanotube, DLC, graphene, Ag nanowire etc)
- Conductive thin film (Metal, ITO etc)
- Diffused sample (or layer)
- Silicon-related epitaxial materials, Ion-implantation sample
- Others: On Request